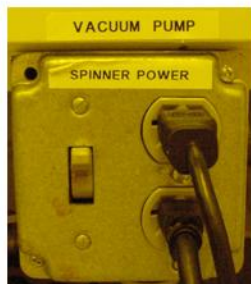


## Prestart Checklist

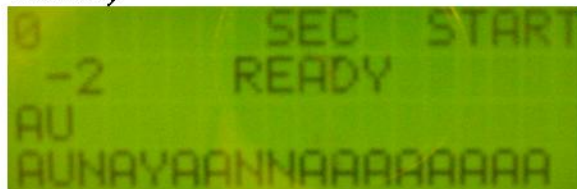


1. Turn on vacuum, the vacuum pump switch is located below sink.



2. Verify the vacuum pressure gauge located next to the HGT machine is greater than 18 inches HG.

3. Turn on the PWM32 controller (the spinner machine located on top of the acid cabinet).



4. Once the controller has been turned on, wait for the machine to show a "ready" state on the LCD Display.

## Procedure

1. Carefully center the wafer face up on the wafer chuck.

2. Press **RECIPE** button and then the NUMBER ON THE 10- KEY PAD for the process which you would like to run. The speeds and times of each of the 10- key pads are shown in the table below.

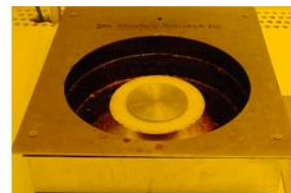
3. Once the recipe had been selected push the GREEN PEDAL button for a test- spin.

4. Observe the wafer and the LCD Display of the PWM32 to ensure that the wafer is spinning at the required speed based on the recipe chosen.

5. squeeze 1 eyedropper-full of photoresist into the center of wafer, about the size of a quarter.

6. Choose the same recipe as chosen in step 2, and repeat step number 3.

7. Once the spinning stops, carefully remove the wafer.



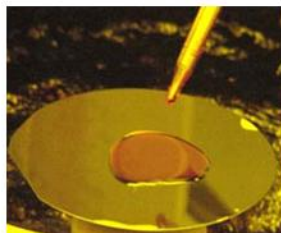
*Wafer Chuck*

Recipe	Step	Speed(RPM)	Time(seconds)
0	1	250	4
	2	3000	10
1	-	3000	60
2	-	4000	60
3	-	5000	60
4	1	1000	1
	2	6000	60
5	1	500	5
	2	2000	30
6	1	500	.5
	2	0	20
	3	3000	30
7	-	2000	60
8	1	5000	10
	2	2000	30
9	-	4000	90

*Number of the process you will be using*



*Foot Pedal  
Reset (red) and Start (green)*



*Use eye dropper to apply  
photoresist in center of wafer*



*Check the time and the speed*